

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



re Application of

Joseph Young J. PAIK

Serial No. 10/665,165

Filed: September 18, 2003

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: Group Art Unit:
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: Examiner:

For: FEEDBACK CONTROL OF A CHEMICAL MECHANICAL POLISHING PROCESS
FOR MULTI-LAYERED FILMS

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom. Copies of any cited U.S. Patents and U.S. Patent Publications are not being submitted in accordance with 37 CFR 1.98(a)(2)(i).

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

In accordance with 37 C.F.R. § 1.97(g) and (h), the filing of this IDS should not be construed as a representation that a search had been made or that information cited is, or is considered to be, material to patentability as defined in 37 C.F.R. § 1.56 (b), or that any cited document listed or attached is (or constitutes) prior art. Unless otherwise indicated, the date of

publication indicated for an item is taken from the face of the item, and Applicant reserves the right to prove that the date of publication is in fact different.

The references listed on Sheet 1 of the attached PTO-1449 Forms were cited in a patentability investigation and/or a corresponding foreign or PCT application relating to the above-referenced application. The remaining references are from potentially related patent applications, and possibly other sources.

No fee is believed to be required; however, the Commissioner is authorized to charge any deficiency in any fees pursuant to 37 CFR § 1.17 associated with this communication and to credit any excess payment to Deposit Account No. 08-0219.

Respectfully submitted,

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Date: 07/16/04

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

INFORMATION DISCLOSURE
CITATION IN AN
APPLICATION
(PTO-1449)

ATTY. DOCKET NO.
007734 FPS/MMCS/APC

SERIAL NO.
10/665,165

APPLICANT
Joseph Young J. PAIK

FILING DATE
September 18, 2003

GROUP

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	3,205,485	09/07/65	Noltingk			10/21/60
	3,229,198	01/11/66	Libby			09/28/62
	3,767,900	10/23/73	Chao et al.			06/23/71
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FILING DATE September 18, 2003				GROUP	
U.S. PATENT DOCUMENTS					
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS
	5,270,222	12/14/93	Moslehi		12/31/90
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	5,546,312	08/13/96	Mozumder et al.				02/24/94
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Joseph Young J. PAIKFILING DATE
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